

Supplementary Figures

Fig. S1. (a) Optical polarising microscope images of a pillar array fabricated in the absence of an electric field, showing the bright and dark states of the device when rotated between crossed polarizers. (b) An illustration of the fabrication of the polymer pillars in a 20 μ m-thick, nematic pi-cell device under the application of an electric field of E = 0.4 V/ μ m. A series of microscope images showing (c) the square and (d) the hexagonal shaped pillar arrays in their bright and dark states when rotated between crossed polarizers under varying electric field strengths.



Fig. S2. A series of microscope images showing the checkerboard-type structure in its dark state between crossed polarizers as the device relaxes back to its equilibrium state upon removal of a 1 V/µm applied electric field.